

Supporting Information

AAO-Assisted Low-Cost Flexible Capacitive Pressure Sensors Based on Double-Sided Nanopillars by Facile Fabrication Method

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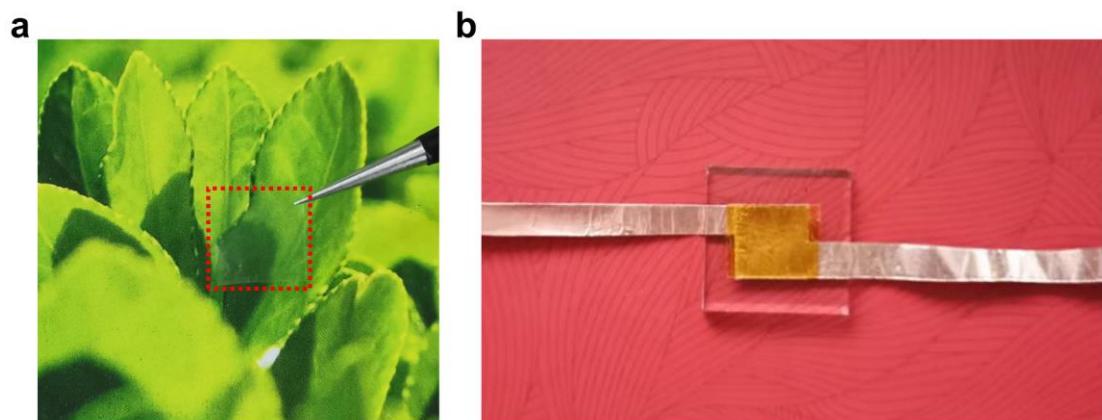


Figure S1. Photographs of (a) a P(VDF-TrFE) film with double-sided nanopillars (marked by a red dotted line) and (b) an assembled pressure sensor.

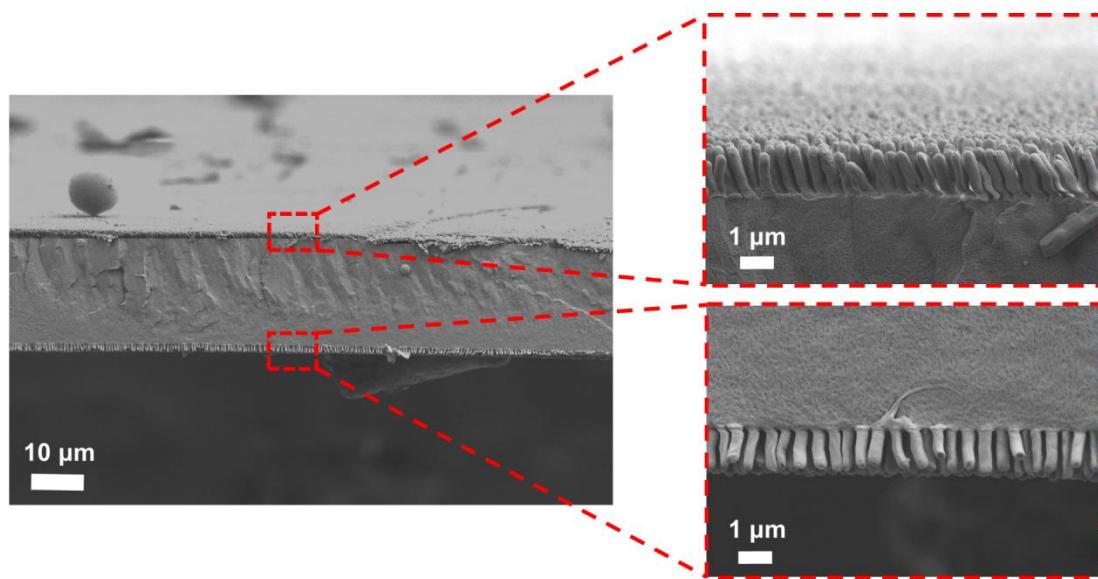


Figure S2. The cross-sectional SEM image and partially enlarged view of the double-sided nanopillars.

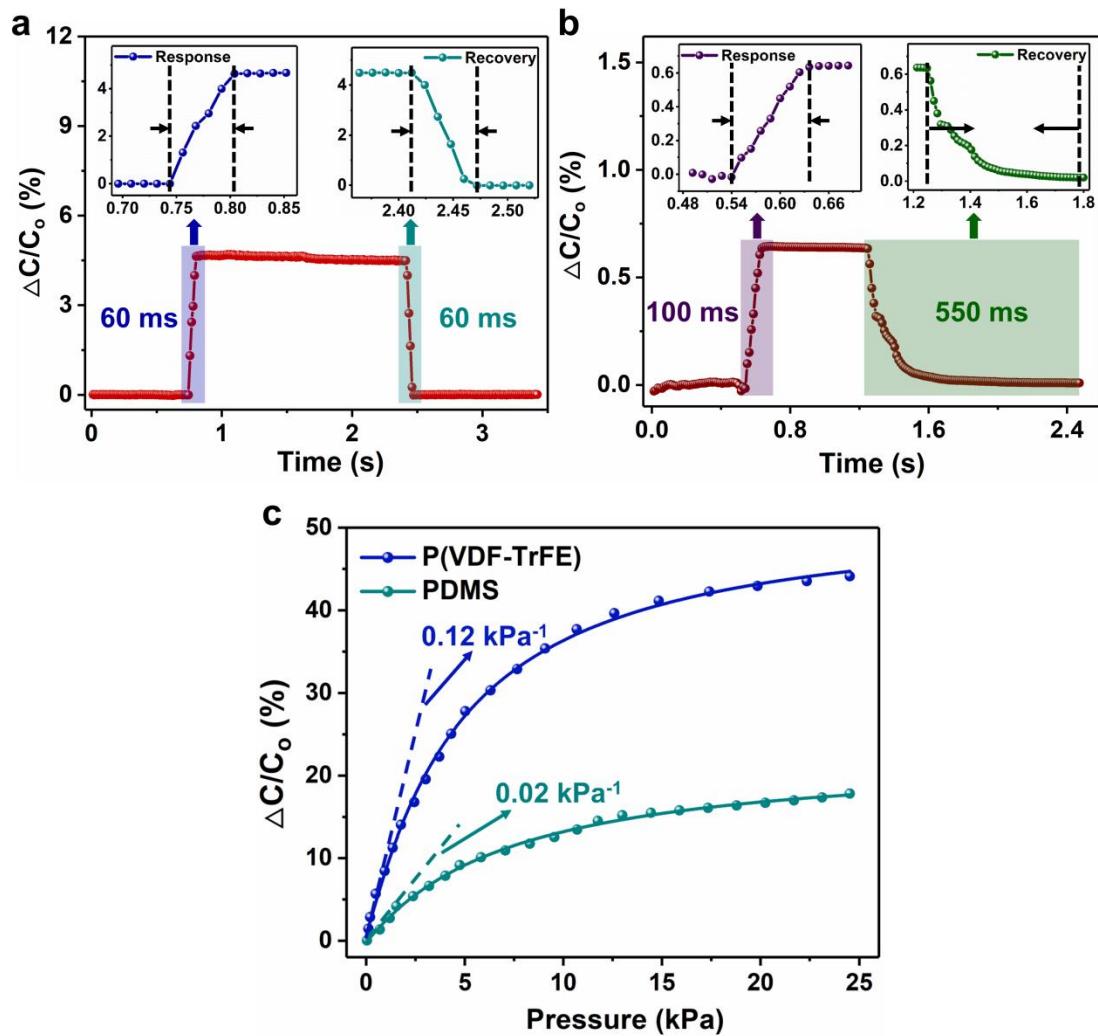


Figure S3. The response and recovery time when a pressure of 0.32 kPa is applied to (a) the P(VDF-TrFE)- and (b) the PDMS-based planar dielectric layer structured sensor, respectively. (c) The relative capacitance variation and sensitivity of the two sensors.

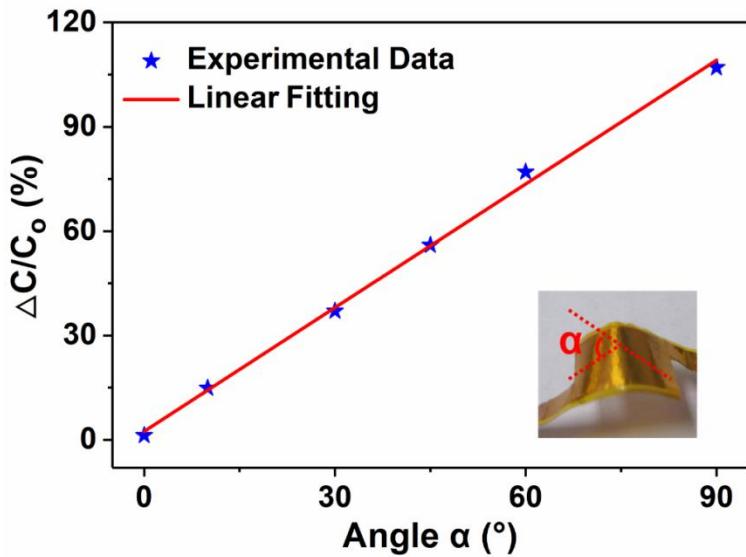


Figure S4. The relationship between the capacitance response and bending angle.

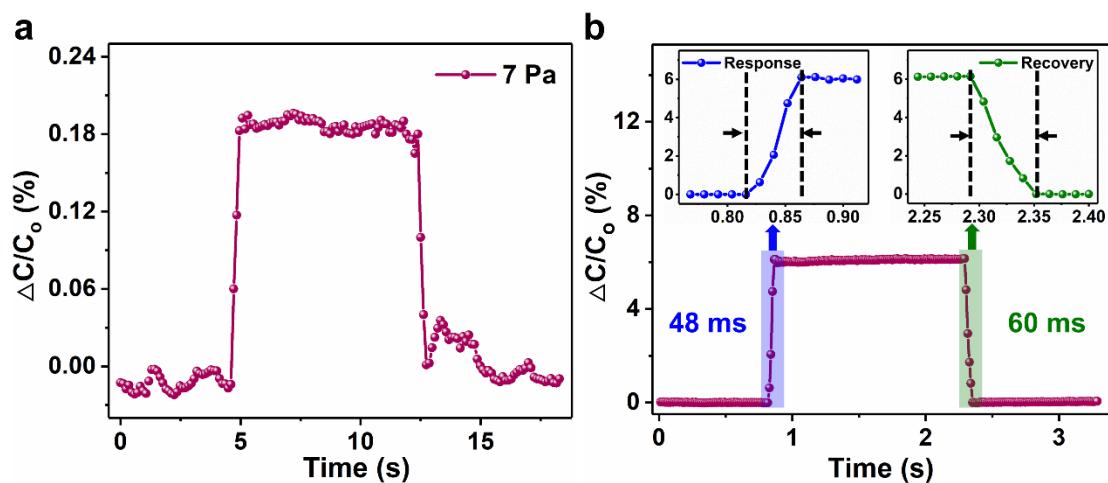


Figure S5. (a) Capacitance response by loading/unloading a slight paper (7 Pa) on the sensor based on single-sided nanopillars to measure the LOD. (b) The response and recovery time when a pressure of 0.32 kPa is applied to the sensor based on single-sided nanopillars.

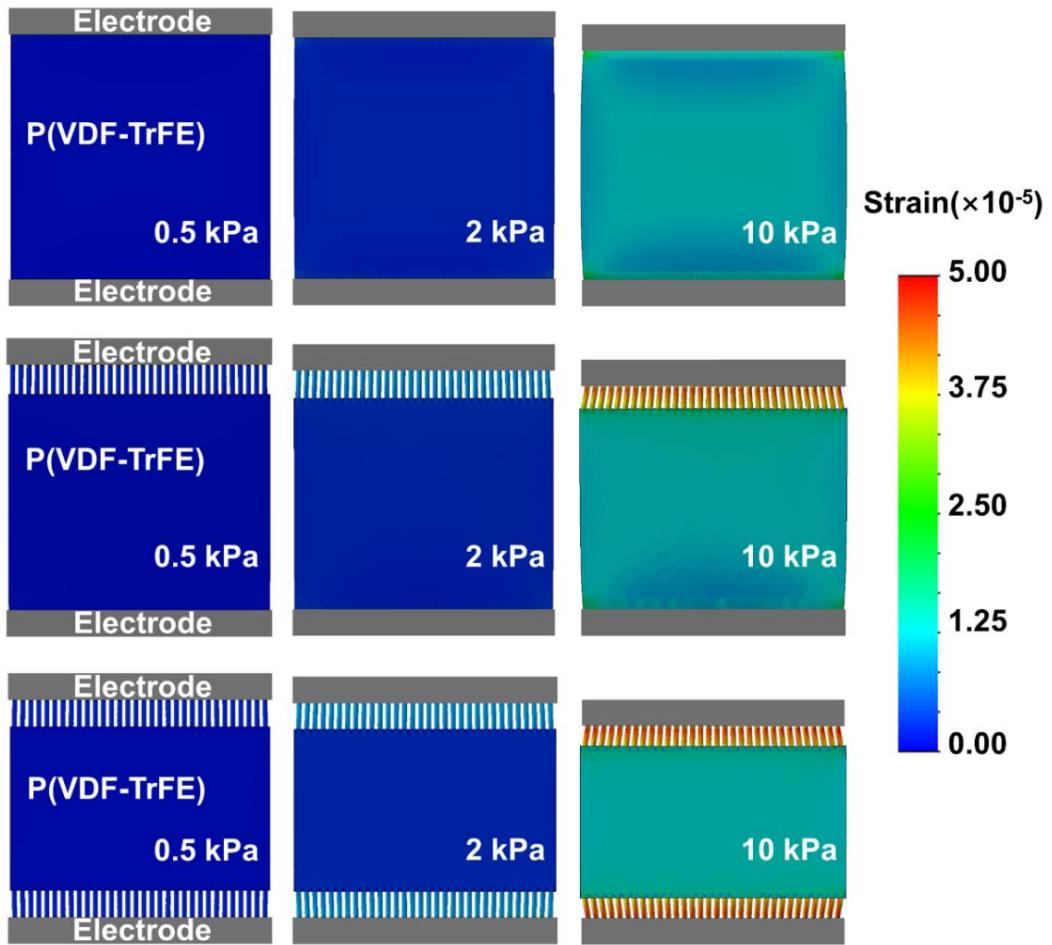


Figure S6. The strain distribution of three sensors under pressures of 0.5, 2, and 10 kPa, obtained by FEA simulation.

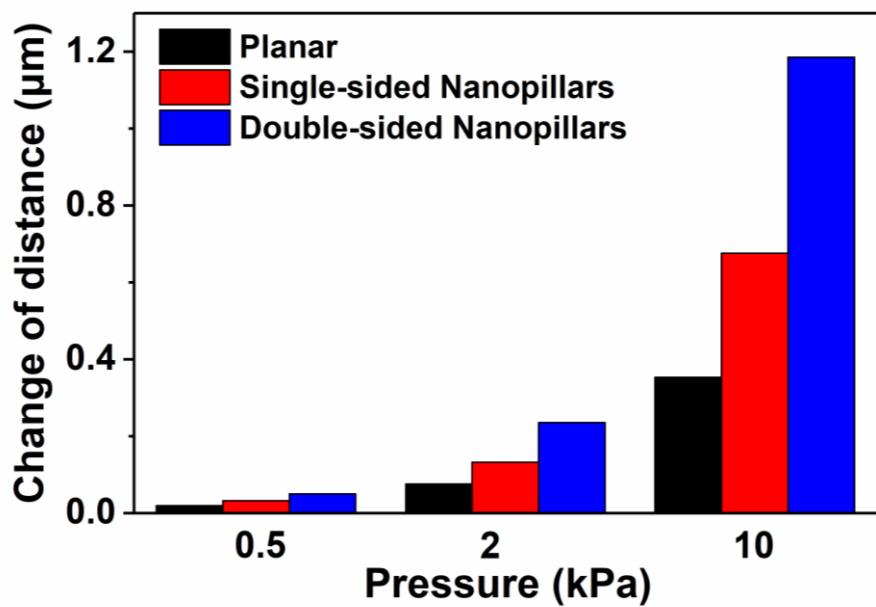


Figure S7. The quantified change of the separation distance under various pressures for each sensor obtained by FEA simulation.

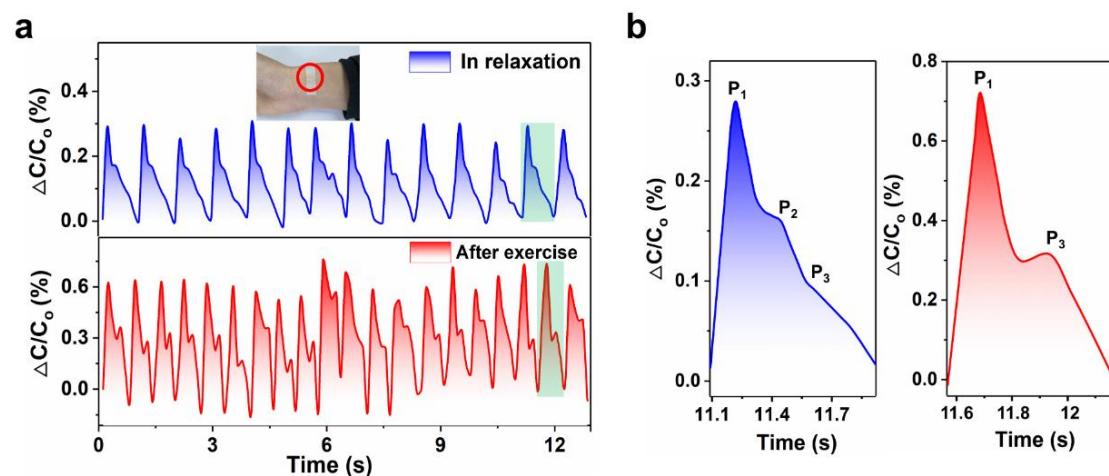


Figure S8. (a) Relative capacitance changes of the wrist pulse before and after exercise. (b)The magnified view of a single pulse before and after exercise, where three typical peaks marked as P₁, P₂ and P₃ correspond to the incident, tidal, and diastolic waves.

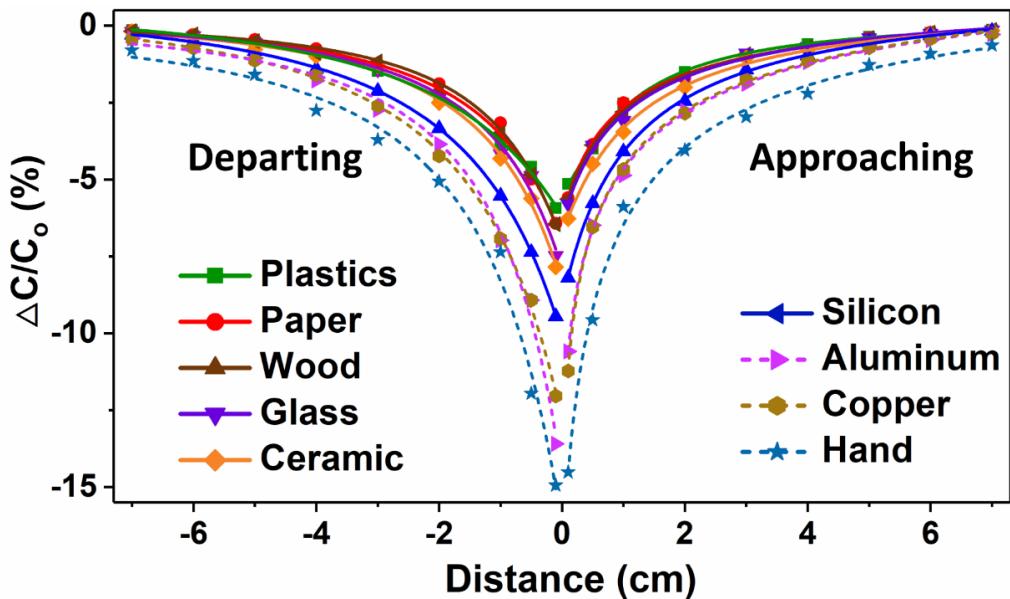


Figure S9. The capacitance responses when the object made of different materials approaching and departing the sensor at various distances.

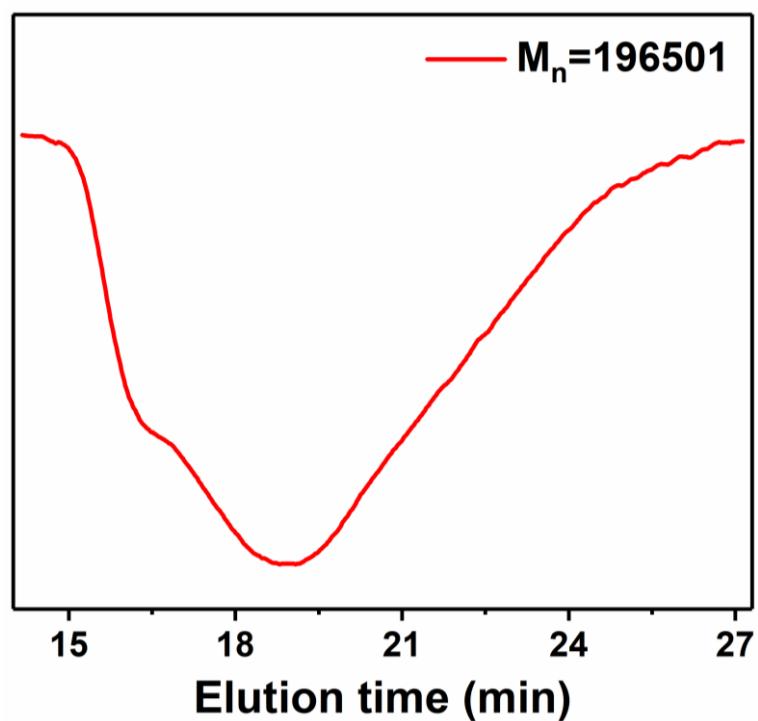


Figure S10. The GPC analysis of P(VDF-TrFE).

Detailed explanation of the letters in Figure 4a

In Figure 4a, ε_p , ε_s , ε_d , ε'_s and ε'_d stand for the dielectric constant of planar dielectric layer, single-sided nanopillars structured dielectric layer, double-sided nanopillars structured dielectric layer, single-sided nanopillars structured dielectric layer after pressing and double-sided nanopillars structured dielectric layer after pressing, respectively. d_p , d_s and d_d indicate the initial distance of planar dielectric layer, single-sided nanopillars structured dielectric layer and double-sided nanopillars structured dielectric layer, respectively. d'_p , d'_s and d'_d mean the changed distance of planar dielectric layer, single-sided nanopillars structured after pressing and double-sided nanopillars structured after pressing, respectively. Δd_p , Δd_s and Δd_d denote the distance variation of planar dielectric layer, single-sided nanopillars structured dielectric layer and double-sided nanopillars structured dielectric layer, respectively.

Table S1. Performance comparison of recent published works based on different flexible pressure sensors.

Sensing materials	Types of devices	Sensitivity (testing pressure)	Working range	Response/Recovery time	Cyclic stability	Ref
Graphene	piezoresistivity	25.1 kPa ⁻¹	16 Pa	120/80 ms	3000	1
rGO	piezoresistivity	178 kPa ⁻¹	42 Pa	261/131 ms	1200	2
PZT	piezoelectricity	0.018 kPa ⁻¹	—	60 ms	5000	3
P(VDF-Tr FE), graphene	piezoelectricity	35 mA/Pa ⁻¹	0.6 Pa	—	5000	4

PET, conductive fiber	triboelect ricity	0.77 V kPa^{-1}	—	80 ms	5000	5
P(VDF-Tr FE), PDMS	triboelect ricity	0.55 V kPa^{-1}	—	—	10000	6
Air-Dielec tric Graphene	transistor	2.05×10^{-4} kPa^{-1}	$250 \text{ Pa} - 3$ MPa	31/49 ms	—	7
Graphene	transistor	0.16 mm^{-1}	—	15 ms	>1000	8
PDMS	capacitan ce	0.42 kPa^{-1} ($<1.5 \text{ kPa}$)	1 Pa	70 ms	1000	9
Eco-flex	capacitan ce	0.01887 $\text{kPa}^{-1} (<45$ kPa)	$35 \text{ Pa} - 700$ kPa	—	7200	10
Water-dilu table polyuretha ne acrylate	capacitan ce	0.61 kPa^{-1} ($<1 \text{ kPa}$)	—	$180/270$ ms	10000	11
Polyethyle ne	capacitan ce	0.09 kPa^{-1} ($<5 \text{ kPa}$)	—	—	—	12
Ecoflex	capacitan ce	0.0224 $\text{kPa}^{-1} (<16$ kPa)	7.3 Pa — 360 kPa	—	—	13
PDMS	capacitan ce	0.6 kPa^{-1} ($<1 \text{ kPa}$)	4.5 Pa	$180/120$ ms	2000	14
Ecoflex with air gap channels	capacitan ce	7.7×10^{-3} $\text{kPa}^{-1} (<10$ kPa)	- $60 \text{ kPa} -$ 20 kPa	—	1000	15
PDMS	capacitan ce	0.171 kPa^{-1} ($<5 \text{ kPa}$)	—	162 ms	1000	16
P(VDF-T rFE)	capacita nce	0.35 kPa^{-1} ($<2 \text{ kPa}$)	$4 \text{ Pa} - 25$ kPa	$48/60 \text{ ms}$	>3000	(this work)

Table S2. GPC Results of P(VDF-TrFE).

M_n	M_w	M_p	M_z	M_{z+1}	M_z/ M_w	M_{z+1}/ M_w
196501	605096	485375	1392398	2148338	2.301119	3.550409

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